

Some History

1906 - triode vacuum tubes
de Forrest

1912-20 - rise of radio
based on vacuum tubes

WWII: radar / magnetron
"Rad Lab" at MIT

1947 - Bell Labs
contact transistor
Bardeen, Brattain
Shockley

1948 - BJT

1959 - MOSFET

1959 - Jack Kilby (TI)
Bob Noyce (Fairchild)
Integrated Circuit

1957 - "traitorous eight"
leave Shockley for
Fairchild - eventually
forming Intel in

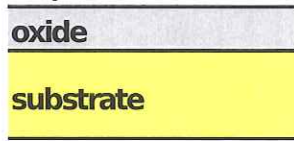
1968 - Gordon
Moore

1971 4 bit microprocessors
Intel 4004
TI TMS 1000

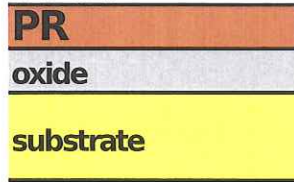
1974 - 8 bit microprocessors

1978 - Intel 8086

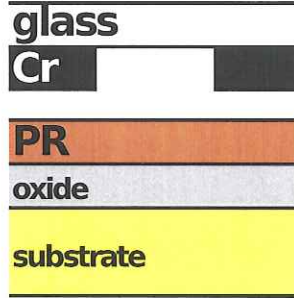
a. Prepare wafer



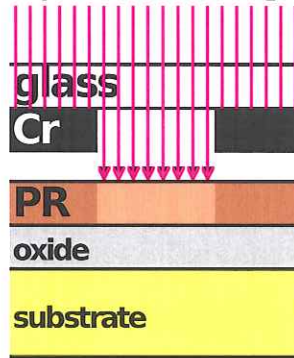
b. Apply photoresist



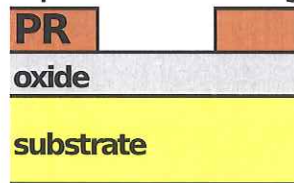
c. Align photomask



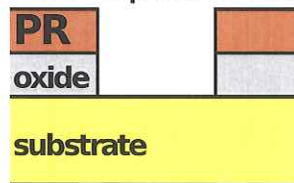
d. Expose to UV light



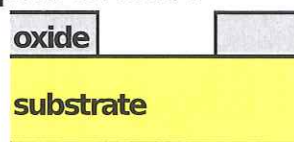
e. Develop and
remove photoresist
exposed to UV light



f. Etch exposed oxide



g. Remove remaining
photoresist



Integrated circuits are
built up/ carved out as
a series of planes.

The features of the plane
are defined by light
shining thru a mask;

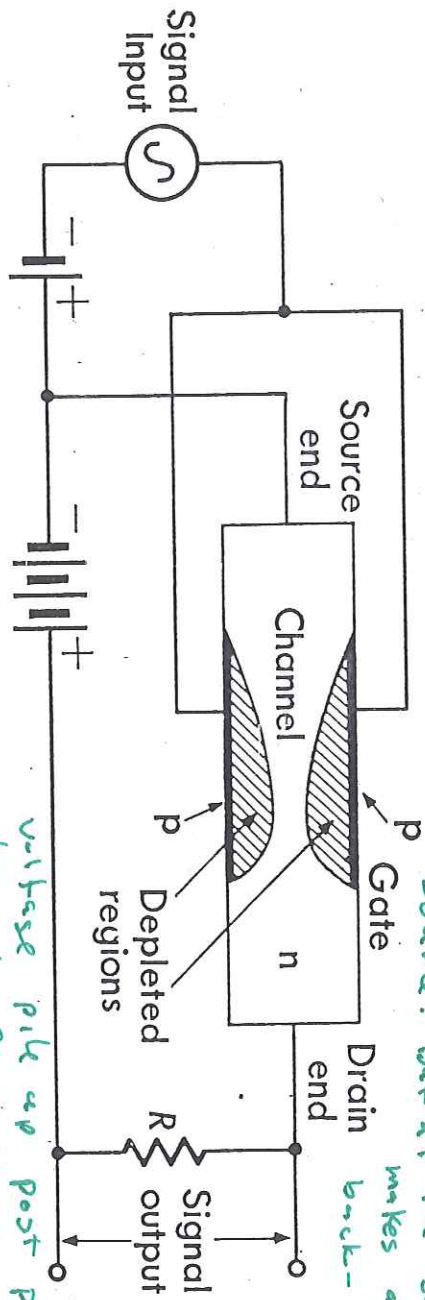
"photoresist" plays the
role of the film - where
exposed to light is "developed"
the layer below is
exposed & may be acted
on (carved out, built up)

Many such layers are required.

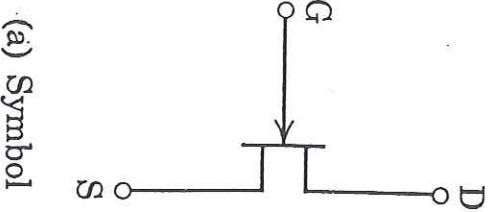
The smallest feature size
is determined by the
wavelength of the light
used - UV & high n
materials yield shorter λ .

From Wiki: "photo lithography"

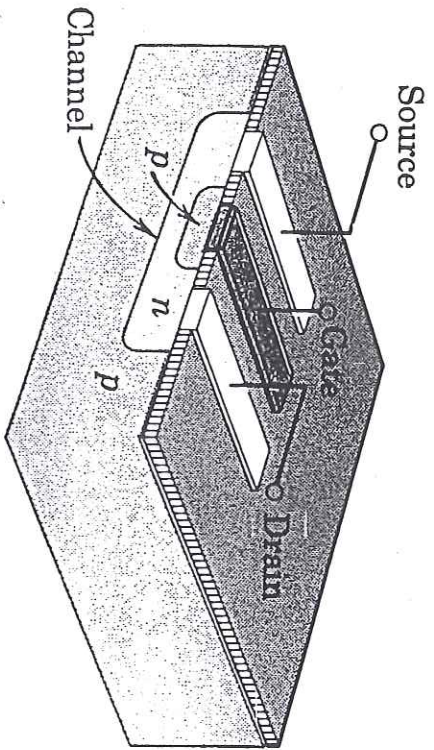
FIG. 3.30. Schematic representation of a field-effect transistor.



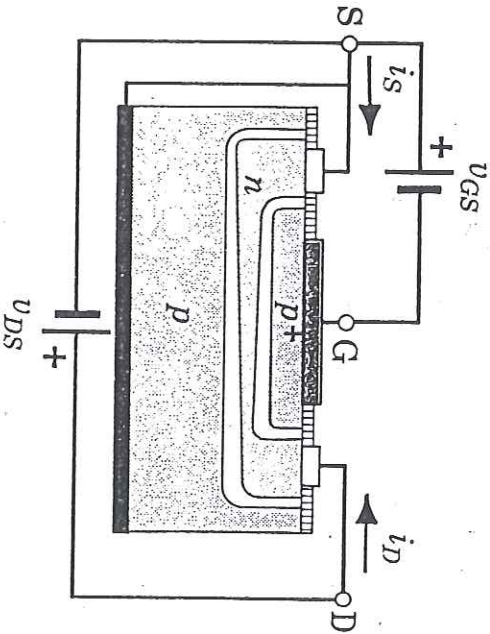
An increasingly positive drain voltage tries to increasingly "suck" electrons from the source. But at the same time this makes an increasingly back-biased pn junction with the gate - the depletion region grows & the channel restricts. when it closes further it increases r_{in} gate voltage pile up post precharge and do not affect the input flux - I_D



(a) Symbol



(b) Typical structure



(c) Channel depletion

Figure 6.1 An n-channel depletion-mode field-effect transistor (JFET).

enhancement mode MOSFET - we make the n channel in p-type material

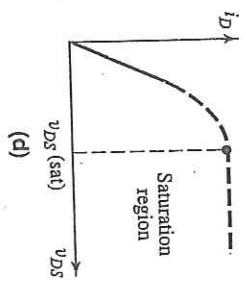
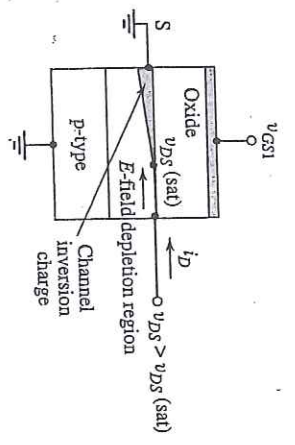
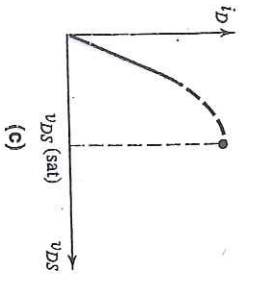
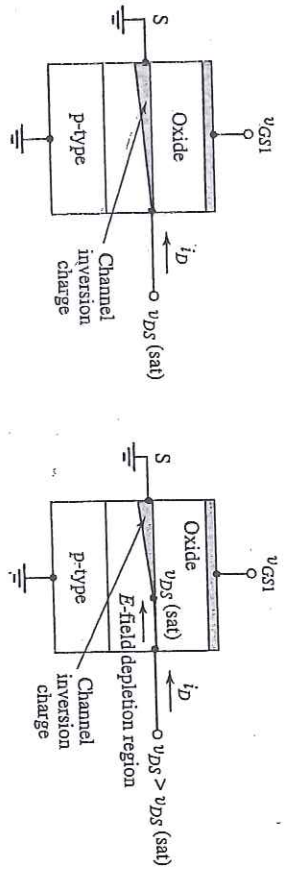
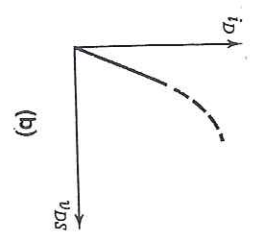
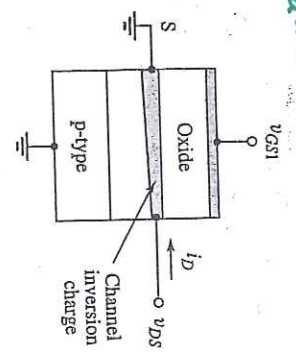
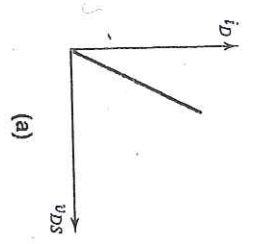
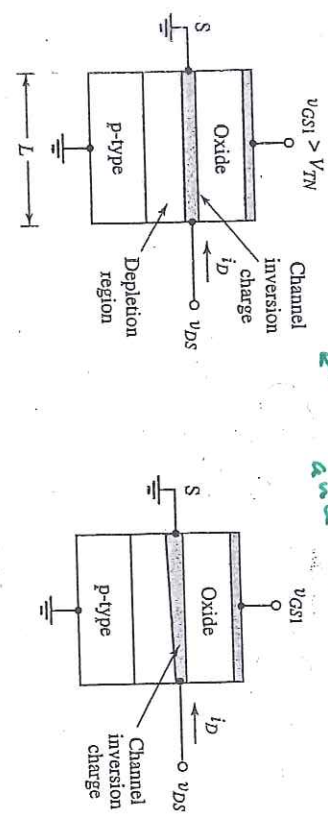


Figure 3.9 Cross section and i_D versus v_{DS} curve for an n-channel enhancement-mode MOSFET when $v_{GS} > V_{TN}$ for (a) a small v_{DS} value, (b) a larger v_{DS} value but for $v_{DS} < v_{DS}(sat)$, (c) $v_{DS} = v_{DS}(sat)$, and (d) $v_{DS} > v_{DS}(sat)$

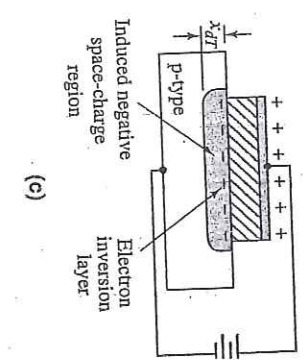
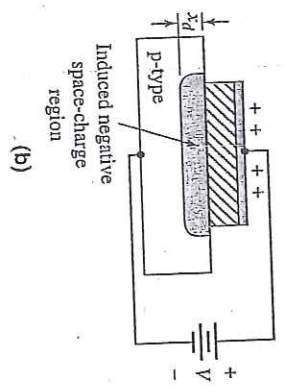
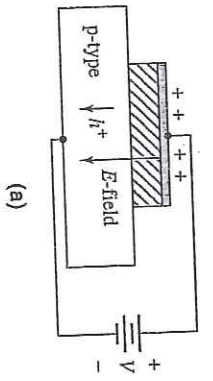
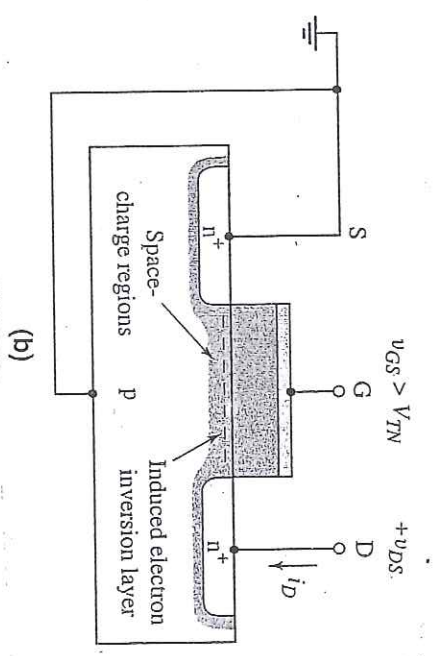
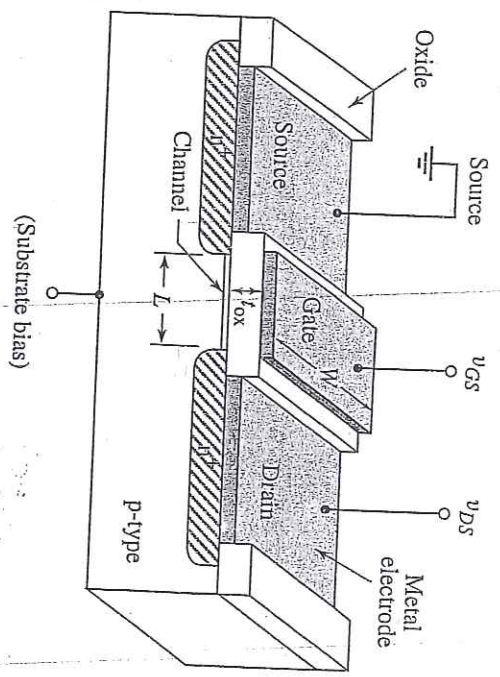


Figure 3.3 The MOS capacitor with p-type substrate: (a) effect of positive gate bias, showing the electric field and charge flow, (b) the MOS capacitor with an induced space-charge region due to a moderate positive gate bias, and (c) the MOS capacitor with an induced electron inversion layer due to a large positive gate bias